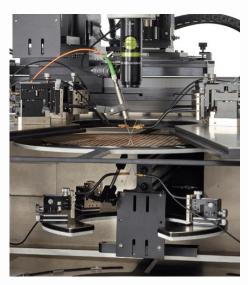


SUCCESSFUL APPLICATION: OPTOELECTRONICS - 1023





Specific Requirements:

The customer needed a semi-automatic 300 mm double-sided probing (DSP) system to characterize several different types and sizes of silicon photonic devices in a shielded environment. The system had to test 150 mm, 200 mm and 300 mm wafers and individual die.

SemiProbe Solution:

- PS4L SA-12 semi-automatic 300 mm probe system:
 - DSP configuration
 - o 300 mm programmable X, Y, Z and theta stage
 - Large travel gantry to accommodate a few different types of optics and instruments with independently controlled X, Y, and Z movements – manual and programmable
 - PILOT Software Suite Navigator, Wafer Map and Autoalign
 - Vibration isolation table
- Universal carrier plate for different sized die, partial wafers and whole wafers up to 300 mm
- Localized Environmental Chamber (LEC) with top-hat to provide dark and EMI shielded environment
- Detector mounted on a small travel programmable stage for optimization of output light collection
- Non-contact height measurement sensor
- Topside and bottom-side optics and cameras
- Manual manipulators for top-side and bottom-side probing
- Probe card holder
- Test Instrumentation Racks